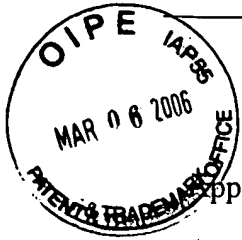


1763  
IFW

Applicant : Masahiko NAKAMORI, et al.  
App. No : 10/536,621  
Filed : May 26, 2005  
For : POLISHING PAD AND METHOD OF  
PRODUCING SEMICONDUCTOR  
DEVICE  
Examiner : Unknown  
Art Unit : 1763

## CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

March 2, 2006

(Date)

  
Katsuhiro Arai, Reg. No. 43,315COMMUNICATION

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Please be advised that a transliteration error in the spelling of the sixth named inventor's name is discovered. The sixth named inventor's name of record is Kimihiro Watanabe which was incorrectly transliterated from the original Japanese name and which should be Masahiro Watanabe.

The undersigned respectfully requests to correct the sixth inventor's first name to -- Masahiro-- in the file of the U.S. Patent and Trademark Office.

No fee is believed to be required for filing the communication, however, if any fees are required, please charge them to Account No. 11-1410,

Respectfully submitted,

KNOBBE, MARTENS, OLSON &amp; BEAR, LLP

Dated: March 2, 2006

By:

  
Katsuhiro Arai  
Registration No. 43,315  
Attorney of Record  
Customer No. 20,995  
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